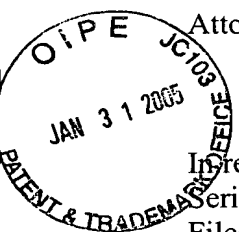


1Fw 1762



Attorney's Docket No. 5308-157IP2

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Das et al.

Confirmation No.: 3570

Serial No.: 10/045,542

Group Art Unit: 1762

Filed: October 26, 2001

Examiner: Kirsten Jolley

For: METHOD OF FABRICATING AN OXIDE LAYER ON A SILICON CARBIDE
LAYER UTILIZING AN ANNEAL IN A HYDROGEN ENVIRONMENT

Date: January 28, 2005

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

Applicants provide the present Amendment to address the issues raised in the Official Action mailed October 28, 2004.

It is not believed that an extension of time and/or additional fee(s)-including fees for net addition of claims-are required, beyond those that may otherwise be provided for in documents accompanying this paper. In the event, however, that an extension of time is necessary to allow consideration of this paper, such an extension is hereby petitioned under 37 C.F.R. §1.136(a). Any additional fees believed to be due in connection with this paper may be charged to our Deposit Account No. 50-0220.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 6 of this paper.